

ABSTRACT

The invention relates to a ceramic joint body and a method of producing the same and a ceramic structural body for a semiconductor wafer, and is particularly used in a semiconductor producing apparatus or an inspection apparatus such as a hot plate (ceramic heater), an electrostatic chuck, a wafer prober or the like, and basically relates to a joint body obtained by joining two or more same or different ceramic bodies, characterized in that ceramic particles grown are existent in joint interfaces of the ceramic bodies so as to infiltrate into the ceramic bodies located at both sides around the interface and the layer of a concentrated sintering aid is eliminated from the joint interface.



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